EAST Search History

EAST Search History (Prior Art)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S144	1	S142 and S143	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:50
S143	1519	(TEOS or TMOS or silicon organic or silicone) same (thickness) same (".mu." or micrometer)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:50
S142	479	S139 and S141	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:49
S141	40642	S137 and S140	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:49
S140	617498	(light extract$4 or scatter$4 or rough$3 near2 surface or uneven near2 surface)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:49
S139	602394	(matsushita electric).as.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:48
S138	95	S137 and S136	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:46
S137	339017	(light-emitting OR light emitting OR electroluminescen$2 OR electro-luminescen$2) ADJ (diode OR device OR apparatus OR structure)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:46

S136	3173	((fukshima near2 hiroshi) or (masao near2 kubo) or (akira near2 inoue) or (kenichiro near2 tanaka) or (mikio neare masui) or (shinji near2 matsui)).inv.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 22:45
S125	122	S103 and pitch	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 19:29
S124	98	S114 and S103	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 19:29
S123	460	S122 and (@ad<"20031112" OR @pd<"20050412")	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:31
S122	1208	S114 and S120 and S105	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:31
S121	40642	S114 and S120	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:31
S120	617498	(light extract$4 or scatter$4 or rough$3 near2 surface or uneven near2 surface)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:30
S119	1092	S118 and (@ad<"20031112" OR @pd<"20050412")	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:29
S118	2478	S114 and S105	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:29

S117	136	S116 and (@ad<"20031112" OR @pd<"20050412")	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:29
S116	472	S104 and S114 and S105	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:28
S115	6013	S104 and S114	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:28
S114	339017	(light-emitting OR light emitting OR electroluminescen$2 OR electro-luminescen$2) ADJ (diode OR device OR apparatus OR structure)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:27
S113	6	S111 and S112	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S112	24318	(master or mold or imprint) SAME etch$4	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S111	200	S110 NOT S107	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S110	293	S109 and (@ad<"20031112" OR @pd<"20050412")	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S109	1020	S108 and (light extracti$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26

S108	1635660	master or mold or imprint	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S107	110	S106 and (@ad<"20031112" OR @pd<"20050412")	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S106	394	S105 and (light extract$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S105	34046	(mold$4 SAME etch$4)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S104	112853	(imprint$3) or (soft lithograph$3) or (micromold $3) or (contact print$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S103	1519	(TEOS or TMOS or silicon organic or silicone) same (thickness) same (".mu." or micrometer)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:26
S102	3603	257/E21.503.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:24
S101	2409	257/E21.502.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:24
S100	2151	257/E21.499.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:24

S99	941	438/47.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:21
S98	897	438/26.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:21
S97	2376	438/22.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	ADJ	ON	2009/11/14 17:20

EAST Search History (Interference)

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S135	26	S129 and S131 and (pitch. clm.)	USPAT; UPAD	ADJ	ON	2009/11/14 19:35
S134	4	S129 and S131 and S132	USPAT; UPAD	ADJ	ON	2009/11/14 19:35
S132	577	((TEOS or TMOS or silicon organic or silicone) and (". mu." or micrometer)).clm.	USPAT; UPAD	ADJ	ON	2009/11/14 19:34
S131	32619	((light-emitting OR light emitting OR electroluminescen $2 OR electro-luminescen$2) ADJ (diode OR device OR apparatus OR structure)).clm.	USPAT; UPAD	ADJ	ON	2009/11/14 19:33
S129	24420	(light extract$4 or scatter$4 or rough$3 near2 surface or uneven near2 surface).clm.	USPAT; UPAD	ADJ	ON	2009/11/14 19:32

11/23/2009 2:55:17 PM
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Laser\ fukushima 10575489 LED rough surface by molding.wsp